



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In the application of:

Hiroyuki NIWA et al.

Serial No.: 10/0

10/069,136

Filing Date:

February 22, 2002

For:

POSITIVE TYPE RADIATION-SENSITIVE COMPOSITION AND PROCESS FOR PRODUCING PATTERN WITH THE SAME Examiner: Amanda C. WALKE

Confirmation No.: 1671

Group Art Unit: 1752

AMENDMENT UNDER 37 CFR 1.111

Mail Stop AMENDMENT Commissioner for Patents 2011 South Clark Place Room 1B03, Crystal Plaza 2 Arlington, VA 22202

Sir:

In response to the Office Action dated March 24, 2004, please amend this application as follows:

The claim amendments begin on page 2.

The Remarks begin on page 9.